

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A magnetic recording disk, comprising:
a substrate;
a magnetic recording layer prepared on the substrate; and
an anisotropy-allowing layer provided between the substrate and the magnetic recording ~~disk~~ layer;
the anisotropy-allowing layer allowing magnetic anisotropy to the magnetic recording layer;
the anisotropy-allowing layer being made of nitride of niobium, tantalum, niobium alloy or tantalum alloy; or nitrogen-including niobium, tantalum, niobium alloy or tantalum alloy.
- A1 2. (Currently Amended) A The magnetic recording disk as claimed in claim 1, wherein the surface of the anisotropy-allowing layer ~~being~~ is denaturalized by being ~~exposing~~ exposed to atmospheric gas, nitrogen gas or oxygen gas.
3. (Currently Amended) A method for manufacturing a magnetic recording disk, comprising:
~~a step of preparing a~~ magnetic-recording layer ~~preparation~~ on a substrate; and
~~a step~~ preparing an anisotropy-allowing-layer on the substrate prior to the magnetic-recording layer preparation;
the anisotropy allowing layer allowing magnetic anisotropy to the magnetic recording layer;

the anisotropy-allowing layer being made of nitride of niobium, tantalum, niobium alloy or tantalum alloy; or nitrogen-including niobium, tantalum, niobium alloy or tantalum alloy.

4. (Currently Amended) A The method for manufacturing a magnetic recording disk as claimed in claim 3, further comprising ~~a step~~ exposing the prepared anisotropy-allowing layer to atmospheric gas, nitrogen gas or oxygen gas.

5. (Currently Amended) A The method for manufacturing a magnetic recording disk as claimed in claim 3, wherein the anisotropy-allowing layer ~~being~~ is a film deposited by sputtering as relatively a larger number of sputtered particles having the direction component along the direction of the magnetic anisotropy to allow are incident on the substrate.

6. (Currently Amended) A The method for manufacturing a magnetic recording disk as claimed in claim 4, wherein the anisotropy-allowing layer ~~being~~ is a film deposited by sputtering as relatively a larger number of sputtered particles having the direction component along the direction of the magnetic anisotropy to allow are incident on the substrate.

7. (Currently Amended) A system for manufacturing a magnetic recording disk, comprising:

a magnetic-recording-layer preparation chamber in which a magnetic recording layer is prepared on a substrate;

an anisotropy-allowing layer preparation chamber in which an anisotropy-allowing layer to allow magnetic anisotropy to the magnetic recording layer is prepared on the substrate prior to preparation of the magnetic recording layer; and

a transfer mechanism for transferring the substrate from the anisotropy-allowing layer preparation chamber to the magnetic recording layer preparation chamber;

wherein the anisotropy-allowing layer ~~being~~ is made of nitride of niobium, tantalum, niobium alloy or tantalum alloy; or nitrogen-including niobium, tantalum, niobium alloy or tantalum alloy.

8. (Currently Amended) A The system for manufacturing a magnetic recording disk as claimed in claim 7, further comprising; a gas-exposure chamber in which the prepared anisotropy-allowing layer is exposed to atmospheric gas, nitrogen gas or oxygen gas, prior to preparation of the magnetic recording layer in the magnetic-recording-layer preparation chamber.

9. (Currently Amended) A The system for manufacturing a magnetic recording disk as claimed in claim 7, wherein the anisotropy-allowing layer preparation chamber ~~being~~ is one in which a film as the anisotropy-allowing layer is deposited by sputtering, as relatively a larger number of sputtered particles having the direction component along the direction of the magnetic anisotropy to allow are incident on the substrate.

10. (Currently Amended) A The system for manufacturing a magnetic recording disk as claimed in claim 8, wherein the anisotropy-allowing layer preparation chamber ~~being~~ is one in which a film as the anisotropy-allowing layer is deposited by sputtering, as relatively a larger number of sputtered particles having the direction component along the direction of the magnetic anisotropy to allow are incident on the substrate.

11. (New) The magnetic recording disk as claimed in claim 1, wherein the substrate is disk-shaped.

12. (New) The magnetic recording disk as claimed in claim 1, wherein the substrate is made of glass.

13. (New) The system for manufacturing a magnetic recording disks claimed in claim 7, wherein the substrate is disk-shaped.

PA² 14. (New) The system for manufacturing a magnetic recording disks claimed in claim 7, wherein the substrate is made of glass.

15. (New) The magnetic recording disk as claimed in claim 1, further comprising an underlying layer prepared on the anisotropy-allowing layer.

16. (New) The magnetic recording disk as claimed in claim 15, further comprising an intermediate layer prepared on the underlying layer.

17. (New) The magnetic recording disk as claimed in claim 16, wherein the magnetic recording layer is prepared on the intermediate layer.

18. (New) The system for manufacturing a magnetic recording disk as claimed in claim 7, further comprising an underlying layer prepared on the anisotropy-allowing layer.

19. (New) The system for manufacturing a magnetic recording disk as claimed in claim 18, further comprising an intermediate layer prepared on the underlying layer.

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20. (New) The system for manufacturing a magnetic recording disk as claimed in claim 19, wherein the magnetic recording layer is prepared on the intermediate layer.